

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

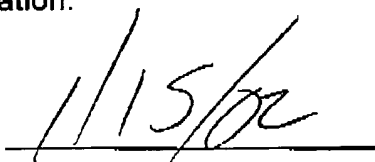
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Inventor Dan G. Custer et al.
Assignee Micron Technology, Inc.
Group Art Unit 1746
Examiner A. Olsen
Attorney's Docket No. MI22-1172
Title: Polishing Systems, Methods of Polishing Substrates, and Methods of Preparing
Liquids for Semiconductor Fabrication Processes

Assistant Commissioner of Patents
Washington, D.C. 20231

ASSOCIATE POWER OF ATTORNEY

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